

Böbel, et al, "In situ film-thickness and temperature monitor", SOLID STATE TECHNOLOGY, vol. 37, no. 8, 08/01/94, pp.55,56,59, Tulsa OK, USA.

AR European Search Report dated December 29, 2000.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.